

CLIPPEDIMAGE= JP360000729A

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TITLE: RESISTANCE HEATING DEVICE

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INVENTOR-INFORMATION:

NAME

IKEGAMI, KAORU

MAEDA, MAMORU

ASSIGNEE-INFORMATION:

NAME

FUJITSU LTD

COUNTRY

N/A

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ABSTRACT:

PURPOSE: To obtain an effective heat conduction between a susceptor and a resistance heating material by a method wherein a conductive susceptor to be used to help heating up a semiconductor wafer and a resistance heating material having an insulating film at the contact part for the purpose of heating up said susceptor are provided.

CONSTITUTION: A susceptor 11 made of carbon, whereon conductive SiC is coated in film thickness of 100~200 μ m or thereabout for the purpose of supplemental heating of a silicon wafer 12, is provided at the lower part of the wafer 12, also carbon heater 15 whereon alumina in film thickness of

100 \sim 200 μ m or thereabout is coated is arranged at the lower part of the susceptor 11 and said carbon heater 15 is connected to a carbon heater electrode 13. The conductive susceptor and the heater are electrically insulated using alumina, and the heat coming from the heater can be transmitted to the susceptor 11 effectively.

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